

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A beam structure comprising:
a semiconductor substrate;
a trench extending into the semiconductor substrate, the trench having walls;
a first conducting layer positioned over the walls of the trench at selected locations; and
a beam positioned ~~with~~ within the trench, the beam being connected at a first portion thereof to the substrate and being movable at a second portion thereof, the second portion being spaced from the walls of the trench by a selected distance; and
a remaining sacrificial layer between the first portion of the beam and the substrate.
2. (Currently Amended) The beam structure ~~in~~ of claim 1, ~~further comprising~~ wherein the remaining sacrificial layer is between the first portion of the beam and the first conducting layer.
3. (Currently Amended) The beam structure of ~~in~~ claim 2 wherein the remaining sacrificial layer comprises an oxide layer.
4. (Currently Amended) The beam structure of ~~in~~ claim 1 wherein the beam is a cantilever beam.
5. (Currently Amended) The beam structure of ~~in~~ claim 1, further comprising a first dielectric layer between the trench and the first conducting layer.

6. (Currently Amended) The beam structure of ~~in~~-claim 5 wherein the first dielectric layer comprises a dual layer of a nitride layer formed on an oxide layer.

7. (Currently Amended) The beam structure of ~~in~~-claim 1, further comprising a second dielectric layer on the beam.

8. (Currently Amended) The beam structure of ~~in~~-claim 1 wherein the beam comprises a second conducting layer and a beam material layer.

9. (Currently Amended) The beam structure of ~~in~~-claim 8 wherein the beam material layer comprises a doped polysilicon layer.

10. (Currently Amended) The beam structure of ~~in~~-claim 8 wherein the second conducting layer comprises a metal layer selected from the group of tungsten, titanium, tantalum, and aluminum.

11. (Currently Amended) The beam structure of ~~in~~-claim 1 wherein the first conducting layer comprises a metal layer selected from the group of tungsten, titanium, tantalum, and aluminum.

12. (Currently Amended) The beam structure of ~~in~~-claim 11 wherein the first conducting layer further comprises a doped polysilicon layer.

13. (Currently Amended) A semiconductor structure comprising:
a semiconductor substrate;
a first trench extending in a first direction, the first trench having walls;
a second trench extending in a second direction, the second trench having walls;
a first conducting layer positioned over the walls of the first and the second trenches at selected locations;

a first beam positioned ~~with~~ within the first trench, the first beam being rigidly connected at a first portion thereof to the substrate and being movable at a second portion thereof, the second portion being spaced from the walls of the first trench by a selected distance; and

a second beam positioned ~~with~~ within the second trench, the second beam being rigidly connected at a first portion thereof to the substrate and being movable at a second portion thereof, the second portion being spaced from the walls of the second trench by a selected distance.

14. (Currently Amended) The semiconductor structure ~~in~~ of claim 13 wherein the length of the first beam is different from the length of the second beam.

15. (Currently Amended) The semiconductor structure ~~of~~ in claim 13 wherein the width of the first beam is different from the width of the second beam.

16. (Currently Amended) The semiconductor structure ~~of~~ in claim 13 wherein the width of the first trench is different from the width of the second trench.

17. (Currently Amended) The semiconductor structure ~~of~~ in claim 13 wherein the thickness of the first beam is different from the thickness of the second beam.

18. (Currently Amended) The semiconductor structure ~~of~~ in claim 13 wherein the first direction is parallel to the second direction.

19. (Currently Amended) The semiconductor structure ~~of~~ in claim 13 wherein the first direction is perpendicular to the second direction.

20. (Currently Amended) The semiconductor structure ~~of~~ in claim 13 wherein the first direction and the second direction are in an arrangement so that the first trench and the second trench have a common radius from a common point.

21. (Currently Amended) The semiconductor structure of ~~in~~-claim 20 wherein the first beam is perpendicular to a first line extending from the center of a circle and the second beam is perpendicular to a second line extending from the center of the same circle.

22. (Currently Amended) The semiconductor structure of ~~in~~-claim 20 wherein the first beam is parallel to and on a first line extending from the center of a circle and the second beam is parallel to and on a second line extending from the center of the same circle.

23. (Currently Amended) The semiconductor structure of ~~in~~-claim 13, further comprising a first dielectric layer between the first trench and the first conducting layer, and between the second trench and the first conducting layer.

24. (Currently Amended) The semiconductor structure of ~~in~~-claim 13, further comprising a first remaining sacrificial layer between the first portion of the first beam and the first conducting layer, and between the first portion of the second beam and the first conducting layer.

25. (Currently Amended) An integrated circuit on a semiconductor substrate comprising:

a sensor including:

a trench extending from a first surface into the substrate, the trench having walls,

a first conducting layer positioned over the walls of the trench at selected locations, and

a beam positioned ~~with~~-within the trench, the beam being connected at a first portion thereof to the substrate and being movable at a second portion thereof, the second portion being spaced from the walls by a selected distance; and

a semiconductor circuit on the substrate having a first node coupled to the first conducting layer and a second node coupled to the beam layer, the semiconductor circuit configured to detect electrical contact between the beam and the trench.

26. (Currently Amended) The integrated circuit ~~of in-~~claim 23 wherein the sensor further comprises a first dielectric layer between the trench and the first conducting layer.

27. (Currently Amended) The integrated circuit ~~of in-~~claim 23 wherein the sensor further comprises a remaining sacrificial layer between the first portion of the beam and the first conducting layer.

28.-31. (Cancelled)

32. (Currently Amended) The method ~~in-of~~ claim 26, ~~further comprising~~⁴⁸ wherein the deflecting step comprises:

applying an acceleration force to the substrate so as to deflect the beam to ~~electrically contact with~~ the wall of the trench.

33. (Currently Amended) The method ~~in-of~~ claim 26, ~~further comprising~~⁴⁸ wherein the deflecting step comprises:

applying a temperature variation from a first temperature to a second temperature to the substrate so as to deflect the beam to ~~electrically contact with~~ the wall of the trench.

34. (Currently Amended) A semiconductor structure comprising:
a semiconductor substrate;
a first trench extending in a first direction, the first trench having walls;
a second trench extending in a second direction, perpendicular to the first direction, the second trench having walls;
a first conducting layer positioned over the walls of the first and the second trenches at selected locations;
a first beam positioned ~~with~~ within the first trench, the first beam being connected at a first portion thereof to the substrate and being movable at a second portion thereof, the second portion being spaced from the walls of the first trench by a selected distance;

a second beam positioned ~~with~~within the second trench, the second beam being connected at a first portion thereof to the substrate and being movable at a second portion thereof, the second portion being spaced from the walls of the second trench by a selected distance; and

a third beam that is parallel to the surface of the semiconductor substrate having its primary axis of motion perpendicular to the surface of the substrate.

35. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the length of the first beam is the same as the length of the second beam.

36. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the width of the first beam is the same as the width of the second beam.

37. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the width of the first trench is the same as the width of the second trench.

38. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the thickness of the first beam is the same as the thickness of the second beam.

39. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the length of the first beam is the different from the length of the third beam.

40. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the width of the first beam is the different from the width of the third beam.

41. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the thickness of the first beam is the different from the thickness of the third beam.

42. (Currently Amended) The semiconductor structure of ~~in~~-claim 34 wherein the third beam is built in a third trench.

43. (Currently Amended) The semiconductor structure of ~~in~~-claim 42 wherein the width of the first trench is different from the width of the third trench.

44. (Currently Amended) The semiconductor structure of ~~in~~-claim 42 wherein the depth of the first trench is different from the depth of the third trench.

45. (New) The structure of claim 13 further comprising:
a circuit configured to detect an electrical connection between the first beam and the first conducting layer and between the second beam and the first conducting layer.

46. (New) The structure of claim 45 wherein the circuit is formed in the semiconductor substrate.

47. (New) The beam structure of claim 1 further comprising:
a circuit configured to detect electrical contact between the second portion of the beam and the first conducting layer.

48. (New) A method, comprising:
deflecting a beam positioned within a trench formed in a semiconductor substrate, a first portion of the beam fixed to the substrate and a second portion movable with respect to the substrate; and
detecting contact between the second portion of the beam and a wall of the trench.

49. (New) The method of claim 48 wherein the detecting step comprises detecting an electrical contact between the beam and the wall of the trench.

50. (New) A beam structure comprising:
a semiconductor substrate;
a trench extending in the semiconductor substrate;

a beam positioned within the trench, coupled at a first portion thereof to the substrate and movable at a second portion thereof, with respect to the substrate; and

means for detecting contact between the second portion of the beam and a wall of the trench.

51. (New) The structure of claim 50 wherein the detecting means comprises an electrical circuit having a first input coupled to the beam and a second input coupled to the wall of the trench, the electrical circuit configured to detect electrical continuity between the first and second inputs.

52. (New) The structure of claim 50 wherein the beam is coupled at a third portion to the substrate, and wherein the second portion is between the first and third portions.